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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/056,017	01/28/2002	W. Thomas Novak	06550006AA	2182
759	90 09/04/2003			
Whitham, Curtis & Christofferson, PC			EXAMINER	
Reston, VA 20	ills Road, Suite 340 190		HASHMI, ZIA R	
			· ART UNIT	PAPER NUMBER
		• .	2881	
			DATE MAILED: 09/04/2003	

Please find below and/or attached an Office communication concerning this application or proceeding.

			<u>4//W</u>
	Application No.	Applicant(s)	
	10/056,017	NOVAK ET AL.	
Office Action Summary	Examiner	Art Unit	
	Zia R. Hashmi	2881	·
Th MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address	
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).  Status	36(a). In no event, however, may a reply be ting within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication D (35 U.S.C. § 133).	n.
1)⊠ Responsive to communication(s) filed on 28 J	lanuary 2002 .		
	is action is non-final.		
3) Since this application is in condition for alloward closed in accordance with the practice under	ince except for formal matters, p Ex parte Quayle, 1935 C.D. 11, 4	rosecution as to the merits in 153 O.G. 213.	is
Disposition of Claims			
4) $\boxtimes$ Claim(s) <u>1-20</u> is/are pending in the application	,		
4a) Of the above claim(s) is/are withdraw	vn from consideration.		
5) Claim(s) is/are allowed.			
6)⊠ Claim(s) <u>1-20</u> is/are rejected.			
7) Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction and/or	r election requirement.		
Application Papers			
9) The specification is objected to by the Examine			
10) ☐ The drawing(s) filed on 28 January 2002 is/are:		-	
Applicant may not request that any objection to the		• •	
11) The proposed drawing correction filed on		oved by the Examiner.	
If approved, corrected drawings are required in rep	•		
12) The oath or declaration is objected to by the Ex	arriirer.		
Priority under 35 U.S.C. §§ 119 and 120		) (-I) (O	
13) Acknowledgment is made of a claim for foreign	i priority under 35 U.S.C. § 119(8	)-(a) or (t).	
a) ☐ All b) ☐ Some * c) ☐ None of:	a barra barra a sanah sad		
1. Certified copies of the priority documents			
2. Certified copies of the priority documents	• •		
<ul> <li>3. Copies of the certified copies of the prior</li> <li>application from the International But</li> <li>* See the attached detailed Office action for a list</li> </ul>	reau (PCT Rule 17.2(a)).	-	
14) Acknowledgment is made of a claim for domesti	c priority under 35 U.S.C. § 119(	e) (to a provisional applicati	ion).
<ul> <li>a)  The translation of the foreign language pro</li> <li>15)  Acknowledgment is made of a claim for domesting</li> </ul>			
Attachment(s)	, ,	<del></del>	
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449) Paper No(s)	5) Notice of Informat	/ (PTO-413) Paper No(s) Patent Application (PTO-152)	

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## **DETAILED ACTION**

## Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 1-20 are rejected under U.S.C. 103(a) as being unpatentable over Shigaraki ( Pub. No: 2002/0006675 A1 ), in view of Miwa ( Pub. No: 2002/0071105 A1 ).
- 3. With respect to independent claims 1 and 13, Shigaraki discloses a lithography system (para 0002, lines 1-5 and para 0076, lines 1-2), comprising a reticle chamber having a chamber opening (para 0042, lines 1-7 and 11 in Fig. 1B); a reticle chamber maintenance panel or over which is mounted to the reticle chamber opening (para 0035, lines 3-6, and a reticle stage (para 0042, line 12 and 4 in Fig. 1A) housed within the reticle chamber (para 0042, lines 1-6, and accessible through the reticle chamber opening (para 0038, lines 1-8 and Fig. 1B).
- 4. With respect to dependent claims 6 and 19,, Shigaraki discloses a lithography system comprising a projection optic system, an illuminator optic system; and a reticle table mounted to the reticle stage and positioned between the projection and illuminator optic systems (para 0041, lines 13-14, para 0036, lines 1-6, para 0042, lines 3-8, and 2, 4 and 5 in Fig. 1A). His system further comprises a body structure, which is mounted to a lower portion of the chamber, the projection optic and the illuminator optic being mounted to the body structure during the removal of the reticle table and the stage



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(11b, 11c,11e, and 14 in Fig. 1A).

5. With respect to claims 1-5, 7-18, and 20, Shigaraki fails to disclose a removably mounted maintenance panel mounted to the reticle chamber. Miwa, however, discloses a maintenance panel which is removably mounted to the reticle chamber opening ( para 0034, lines 6-14 and 12 in Fig. 1 ), wherein the chamber opening provides access to the reticle stage ( 11 and 12 in Fig. 1 ).

It would have been obvious to one having ordinary skill in the art at the time of the invention was made to combine the method and apparatus of Shigaraki and Miwas, and add features like reticle chamber angled opening providing access to reticle stage, or pivotably mounted maintenance panel of semi-cylindrical shape, because Miwa teaches (para 0006, lines 4-6) that to achieve higher throughput, the exchange time for reticles and wafers which are frequently exchanged, must also be shortened.

## Conclusion

- 6. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Hattori et al. disclose (Pub. No : US 2002/0074635 A1) an exposure apparatus with an open-close door mechanism
- 7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Zia Hashmi whose telephone number is (703) 305-0419. The examiner can normally be reached between 8.30 AM- 5 PM. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John R. Lee can be reached on (703) 308-4116.

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Zia Hashmi

August 20, 2003

JOHN R. LEE (
SUPERMISORY PATENT EXAMINER
TECHNOLOGY CENTER 2800

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